



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. No. : 10/660,709 Confirmation No. 7653
Applicant : Y. KAWAMURA et al
Filed : September 12, 2003
Title : METHOD FOR POLISHING SURFACE OF
SEMICONDUCTOR DEVICE SUBSTRATE
TC/AU : 1763
Examiner : G.A. Goudreau
Docket No. : ASA-955-02
Customer No.: 24956

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Office Action of October 7, 2005, please amend the above-identified application as follows. A Petition and fee for a three-month Extension of Time also accompanies this response.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks / Arguments begin on page 9 of this paper.